



Docket No.: 49959-118

**PATENT**

#6  
BH  
7-22-02

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of

Lizhong SUN, et al.

Serial No.: 09/645,690

Filed: August 24, 2000

For: CU CMP POLISHING PAD CLEANING

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Group Art Unit: 1746

Examiner: Gentle E. Winter

**RECEIVED**

JUL 18 2002

**TC 1700**

**RESPONSE TO RESTRICTION REQUIREMENT**

Commissioner for Patents  
Washington, DC 20231

Sir:

Noting the Office Action of June 18, 2002 wherein restriction has been required, Applicants hereby elects Group I (method claims 1-18) for prosecution in the above-identified application.

To the extent necessary, a petition for an extension of time under 37 C.F.R. 1.136 is hereby made. Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

MCDERMOTT, WILL & EMERY

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**Date: July 16, 2002**